ABSTRACT

WAFER CLAMPING RING

A wafer clamping ring (100) includes an annular base wall (2) having an inner edge (21) defining a central opening (210). An annular clamping part (23) extends radially outward from the inner edge (21). A wafer confining wall (4) extends axially from the annular base wall (2) around the clamping part (23). A corner formed between the clamping part (23) and the wafer confining wall (4) defines an accommodating space (201) to receive an edge of a wafer (16). Multiple first spacing pads (7) protrude axially from the clamping part (23). Multiple second spacing pads (8) protrude radially from the wafer confining wall (4) to enlarge clearances between the wafer confining wall (4) and the wafer, thereby preventing deposits from getting stuck in the clearances.

Fig. 4